

High intermodulation gain in a micromechanical Duffing resonator

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In this work we use a micromechanical resonator to experimentally study small signal amplification near the onset of Duffing bistability. The device consists of a PdAu beam serving as a micromechanical resonator excited by an adjacent gate electrode. A large pump signal drives the resonator near the onset of bistability, enabling amplification of small signals in a narrow bandwidth. To first order, the amplification is inversely proportional to the frequency difference between the pump and signal. We estimate the gain to be about 15dB for our device.

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Micro/Nanoelectromechanical resonators play a key role in microdevices for applications such as sensing, switching, and filtering [1],[2]. Understanding nonlinear dynamics in such devices is highly important, both for applications and for basic research [3]-[10]. The relatively small force needed for driving a microresonator into the nonlinear regime is usually easily accessible, enabling a variety of useful applications such as frequency mixing [11] and frequency synchronization [12]. Since nano-scale displacement detection is highly challenging, it is desirable to implement an on-chip mechanical amplification mechanism. Previously, mechanical amplification has been achieved using parametric amplification [13],[14]. Alternatively, amplification could be achieved by using a bifurcating dynamical system [15],[16]. In this work, we employ nonlinear frequency mixing near the onset of Duffing bistability to amplify small displacement signals. We demonstrate experimentally high signal gain in this regime and compare with theoretical predictions.

The device under study is a mechanical resonator consisting of a suspended doubly clamped PdAu beam, located adjacent to a static gate electrode. An electron micrograph of the device is shown in the inset of Fig. 1, and its dimensions are given in the figure's caption.

The nonlinear dynamics of the fundamental mode of a doubly clamped beam driven by an external force per unit mass $F(t)$ can be described by a Duffing oscillator equation for a single degree of freedom x [17]

$$\ddot{x} + 2\mu\dot{x} + \omega_0^2(1 + \kappa x^2)x = F(t), \quad (1)$$

where μ is the damping constant, $\omega_0/2\pi$ is the resonance frequency of the fundamental mode, and κ is the cubic nonlinear constant. For small displacement amplitudes, the nonlinearity is originated by beam's mid-plane stretching due to the immovable boundaries, which tend to harden the beam ($\kappa > 0$). For higher amplitudes, however, the contribution of the applied electric force, which tend to soften the beam, becomes dominant.

Generally, for resonators driven using a bias voltage applied to a side electrode, Eq. 1 should contain addi-

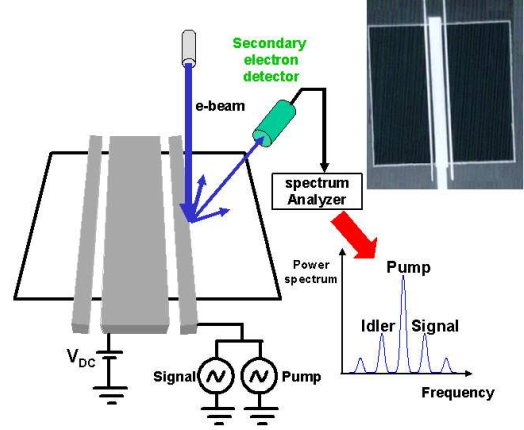


FIG. 1: The experimental setup. The inset shows an electron micrograph of the device, consisting of two suspended doubly clamped micromechanical resonators. Each resonator is of length $l=100\mu\text{m}$, width $w=0.6\mu\text{m}$, and thickness $t=0.25\mu\text{m}$, centered around a gate electrode with $d = 4\mu\text{m}$ gap. The device is mounted inside an SEM operated in a spot mode to detect the resonator's displacement. The displacement signal is probed by a secondary electron detector and measured using a spectrum analyzer.

tional parametric terms [13],[18]. In our case however, the prefactors of these parametric terms is at least one order smaller below threshold, thus negligible.

The device has a quality factor of $Q = \omega_0/2\mu \approx 2000$ (at 10^{-5} torr) and the fundamental mode resonance frequency $\omega_0/2\pi$ is in the range of 560 kHz to 630kHz.

To investigate nonlinear amplification, the resonator is driven by an applied force $F(t) = f_p \cos(\omega_p t) + f_s \cos(\omega_s t + \varphi)$, composed of an intense *pump* with frequency $\omega_p = \omega_0 + \sigma$, amplitude f_p , and a small force (called *signal*) with frequency $\omega_s = \omega_p + \delta$, relative phase φ , and amplitude f_s , where $f_s \ll f_p$ and $\sigma, \delta \ll \omega_0$. This is achieved by applying a voltage of the form $V = V_{dc} + v_p \cos(\omega_p t) + v_s \cos(\omega_s t + \varphi)$ where V_{dc} is a dc bias and $v_s \ll v_p \ll V_{dc}$. The resonator's displacement has spectral components at ω_p , ω_s , and at the intermodulations $\omega_p \pm k\delta$ where k is an integer. The one at frequency $\omega_i = \omega_p - \delta$ is called the idler component, as in nonlinear

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optics.

In the slowly varying envelope method [17], the displacement x is written as

$$x(t) = \frac{1}{2}A(t)e^{i\omega_p t} + c.c., \quad (2)$$

where $A(t)$ is a slowly varying function (relative to the time scale $1/\omega_p$). Substituting Eq. (2) in the equation of motion (1) and neglecting the d^2A/dt^2 term yields

$$\frac{dA}{dt} = -(\frac{\omega_0}{2Q} + i\sigma)A + i\frac{3}{8}\kappa\omega_0 A^2 A^* + \frac{1}{2i\omega_0}(f_p + f_s e^{i(\delta t + \varphi)}). \quad (3)$$

$A(t)$ can be written as

$$A(t) = a_p + a_s e^{i\delta t} + a_i e^{-i\delta t}, \quad (4)$$

where the complex numbers a_p , a_s and a_i are the pump, signal and idler components of $A(t)$ respectively, and $|a_s|, |a_i| \ll |a_p|$. Substituting Eq. (4) in Eq. (3) and keeping small terms up to first order, leads to [15]

$$a_s = \frac{\frac{1}{2\omega_0}f_s e^{i\varphi} - \frac{3}{8}\kappa\omega_0 a_p^2 a_i^*}{\frac{3}{4}\kappa\omega_0 |a_p|^2 - \delta - \sigma + i\frac{\omega_0}{2Q}}, \quad (5a)$$

$$a_i = \frac{-\frac{3}{8}\kappa\omega_0 a_p^2 a_s^*}{\frac{3}{4}\kappa\omega_0 |a_p|^2 - \delta - \sigma + i\frac{\omega_0}{2Q}}. \quad (5b)$$

The pump response $|a_p|$ in the absent of any additional signal is shown in Fig. 2, panels (a),(b) and (c) [15]. Above some critical driving amplitude f_c , the response becomes a multi-valued function of the frequency in some finite frequency range, and the system becomes bistable with jump points in the frequency response. We refer to the onset point of bistability (which is also a saddle-node bifurcation point) as the critical point. When the pump is tuned to the critical point ($\sigma = \sqrt{3}\omega_0/2Q$, $|a_p|^2 = 8/3\sqrt{3}\kappa Q$) [19] and $\delta \rightarrow 0$, we expect high amplification of both signal and idler. In this limit

$$|a_s| \simeq |a_i| \simeq \frac{f_s}{2\omega_0\delta}. \quad (6)$$

Thus, in our model which assumes that $|a_s|$ and $|a_i|$ are small, and takes nonlinearity into account only to lowest order, the amplification diverges in the limit $\delta \rightarrow 0$. When $|a_s|$ and $|a_i|$ become comparable with $|a_p|$, however, the former assumptions are no longer valid and higher order terms have to be taken into account.

The pump, signal, and idler's responses were calculated analytically [15] and are shown in Fig. 2. For a small f_p , the signal's response is nearly Lorentzian, while for $f_p > f_c$, both signal and idler response diverge near the jump points.

The resonators are fabricated using bulk-nano-machining process together with electron beam lithography [20]. The experimental setup is shown in Fig.

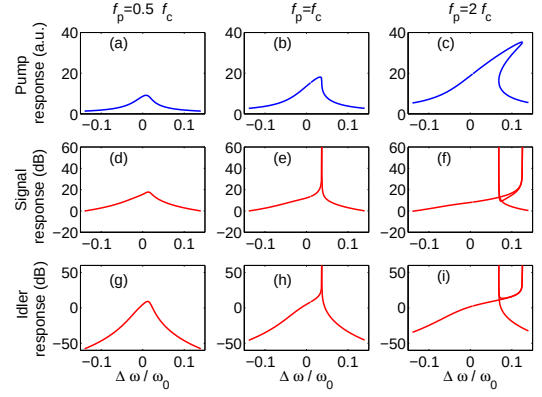


FIG. 2: Calculation of the pump, signal, and idler responses ($|a_p|$, $|a_s|$, $|a_i|$) for vanishing offset frequency δ , shown for sub-critical case $f_p = 0.5f_c$ (a,d,g), critical case $f_p = f_c$ (b,e,h), and over-critical case $f_p = 2f_c$ (c,f,i). The y-axis of the pump is shown in a linear scale while the signal's and idler's response are normalized to the signal's excitation amplitude and are shown in a logarithmic scale. The signal's and idler's response diverge at the critical point and at the jump points. The parameters for this example are $\kappa = 10^{-4} \text{ m}^{-2}$, $\mu = 10^2 \text{ Hz}$, $\omega_0/2\pi = 1 \text{ MHz}$, and $\delta/2\pi = 10 \text{ Hz}$.

1. Measurement of mechanical vibration is done at room temperature, *in-situ* a scanning electron microscope (SEM) where the imaging system of the microscope is employed for displacement detection [20]. The three spectral components ω_p , ω_s , and ω_i of the displacement are measured using a spectrum analyzer.

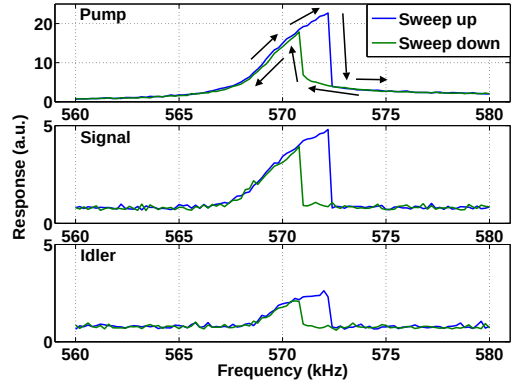


FIG. 3: Simultaneous measurement of the pump, signal and idler spectral components of the mechanical displacement. The excitation frequency is swept upward (blue line) and downward (green line). The arrows in the pump's plot indicate the hysteresis loop. The excitation parameters are: pump ac voltage $v_p = 0.5 \text{ V}$, $v_p/v_s = 6$, frequency offset $\delta/2\pi = 1 \text{ kHz}$ and $V_{dc} = 5 \text{ V}$. The horizontal axis is the pump frequency for all three plots. The pump signal and idler exhibit simultaneous jumps, as expected.

A typical mechanical response is shown in fig. 3. The pump's frequency is swept upward and then back down-

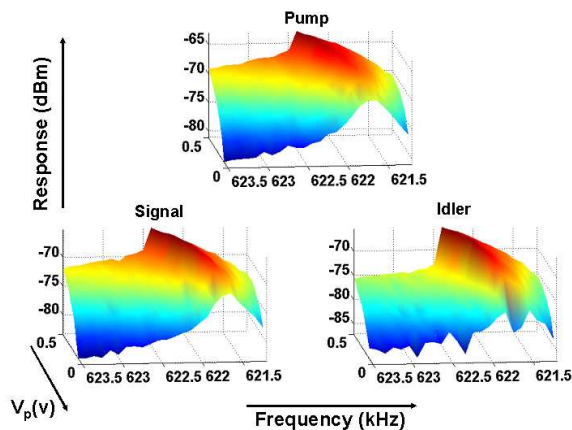


FIG. 4: Mesh plots showing the response of the pump, signal and idler. The horizontal axis is the pump's frequency ω_p , the diagonal axis is the pump's ac voltage v_p and the vertical axis is the response (displacement) axis in logarithmic scale. For each frequency, v_p is scanned from 0 to 0.5V, $v_p/v_s = 6$, $\delta/2\pi = 100$ Hz, $V_{dc} = 5$ V. Note that the pump's response undergoes a jump along a line in the (v_p, ω_p) plane, starting from the bifurcation point. Along the same line, the spectral components of the signal and idler obtain their maximum value.

ward. As expected, we find hysteretic response and simultaneous jumps for the pump, signal, and idler spectral components. In Fig. 4 the mechanical responses of the pump, signal and idler are depicted as a function of the pump's frequency $\omega_p/2\pi$ and the pump's ac voltage v_p . For each frequency, the voltage v_p is scanned from 0 to 0.5 V. The results show a good agreement with theory. As expected, we observe high signal amplification near the jump points. The amplification can be quantified in logarithmic scale as

$$G \equiv 20 \log\left(\left|\frac{a_{s,pump_on}}{a_{s,pump_off}}\right|\right). \quad (7)$$

The highest value of G , obtained near one of the jump points is 15dB. Note, however, that this value is an underestimation of the actual gain due to nonlinearity of our displacement detection scheme.

In conclusion, we have shown that a Duffing micromechanical resonator, driven into the bistability regime, can be employed as a high gain narrow band mechanical amplifier.

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